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Gutierrez

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(54) **SEAL RING FOR INTEGRATED CIRCUITS**
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(*) Notice: Subject to any disclaimer, the term of this patent is extended or adjusted under 35 U.S.C. 154(b) by 0 days.

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(52) **U.S. Cl.** **257/547**; 257/373; 257/409; 257/490; 257/494; 257/495; 257/544
(58) **Field of Search** 257/547, 659, 257/600, 500, 372, 373, 508

(57) **ABSTRACT**

The present invention is directed to a seal structure and a method for forming a seal structure for a semiconductor die. An elongate region which is electrically isolated from the remainder of the substrate, such as a well region of a conductivity type opposite that of the substrate, extends around the major portion of the periphery of the substrate. A gap is left between the two ends of the elongate region along the minor portion of the periphery of the substrate not covered by the elongate region. A conductive seal ring is formed around the periphery of the substrate at the elongate region and spans the gap between the ends of the elongate region. The substrate of the semiconductor die is only brought into electrical contact with the seal ring at the gap between the ends of the elongate region.

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20 Claims, 3 Drawing Sheets

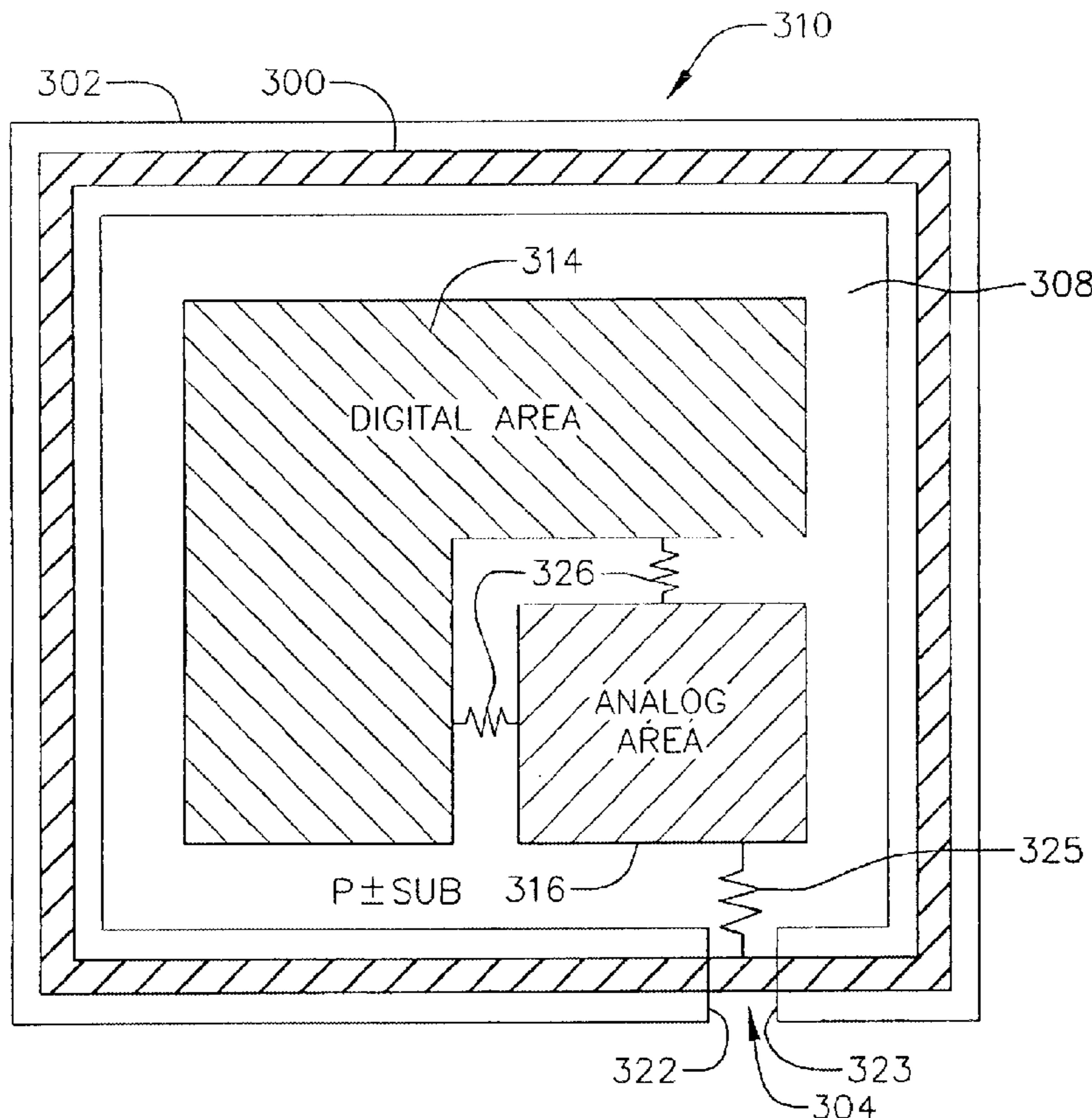
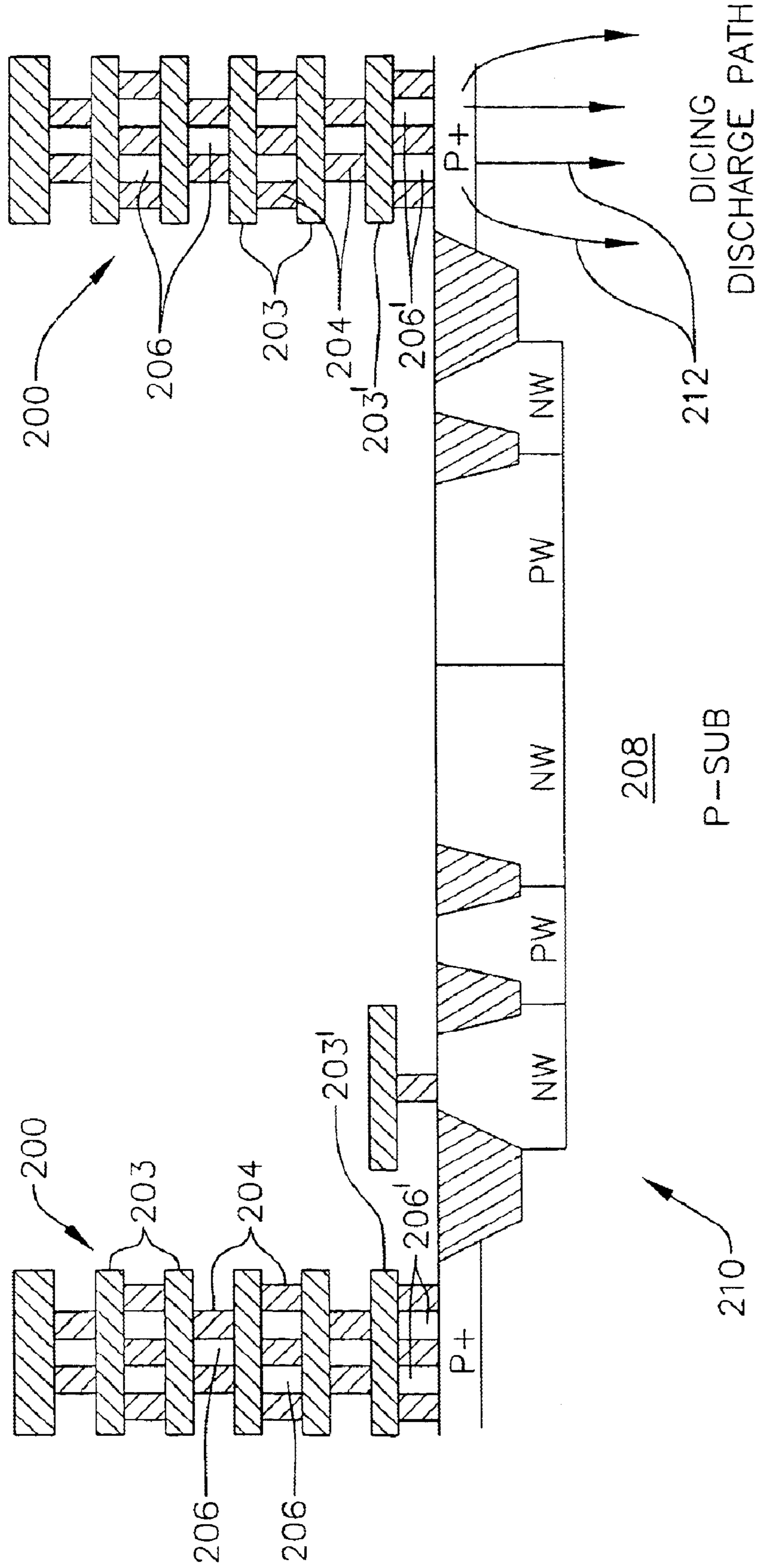


FIG. 1
PRIOR ART



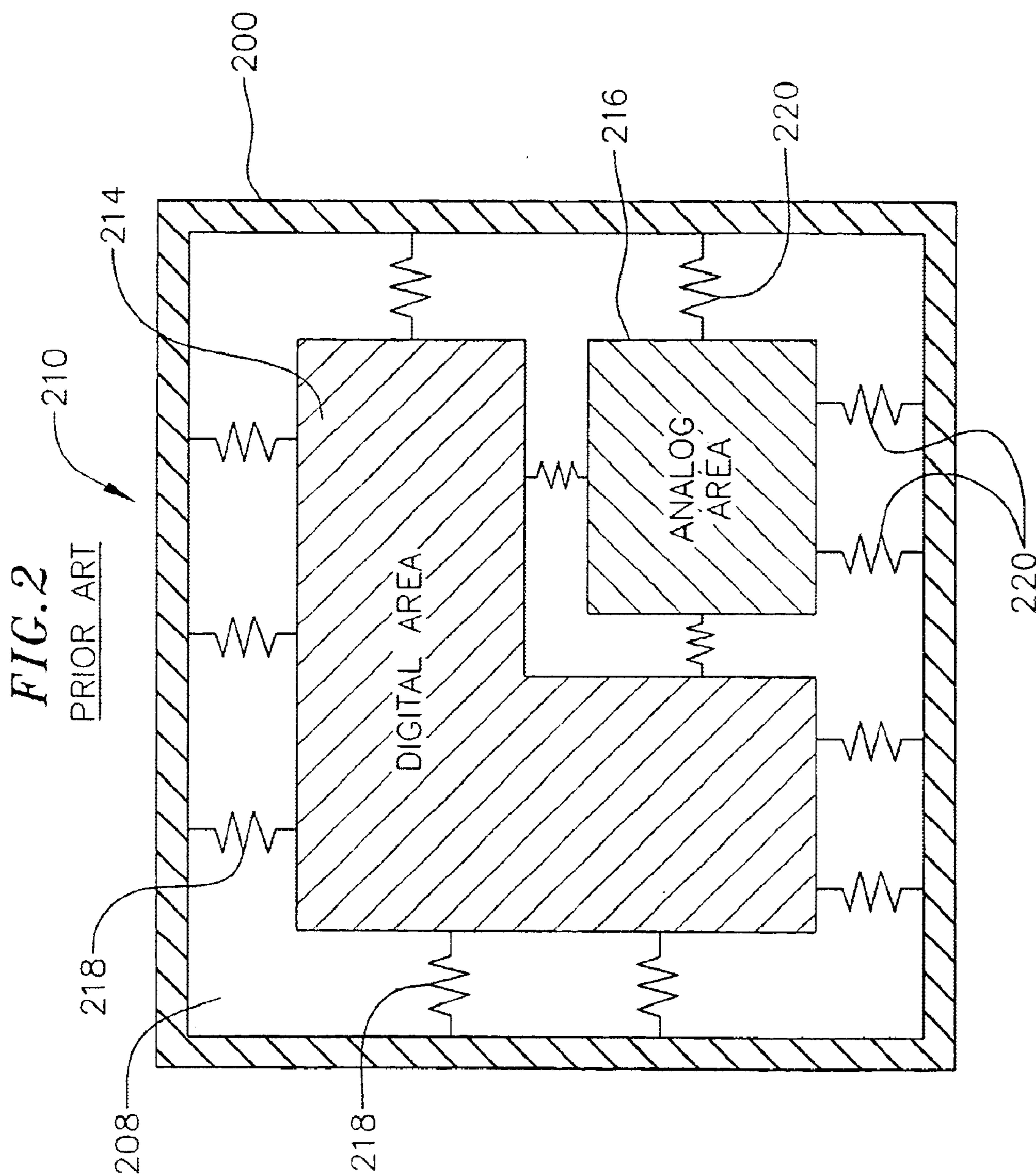
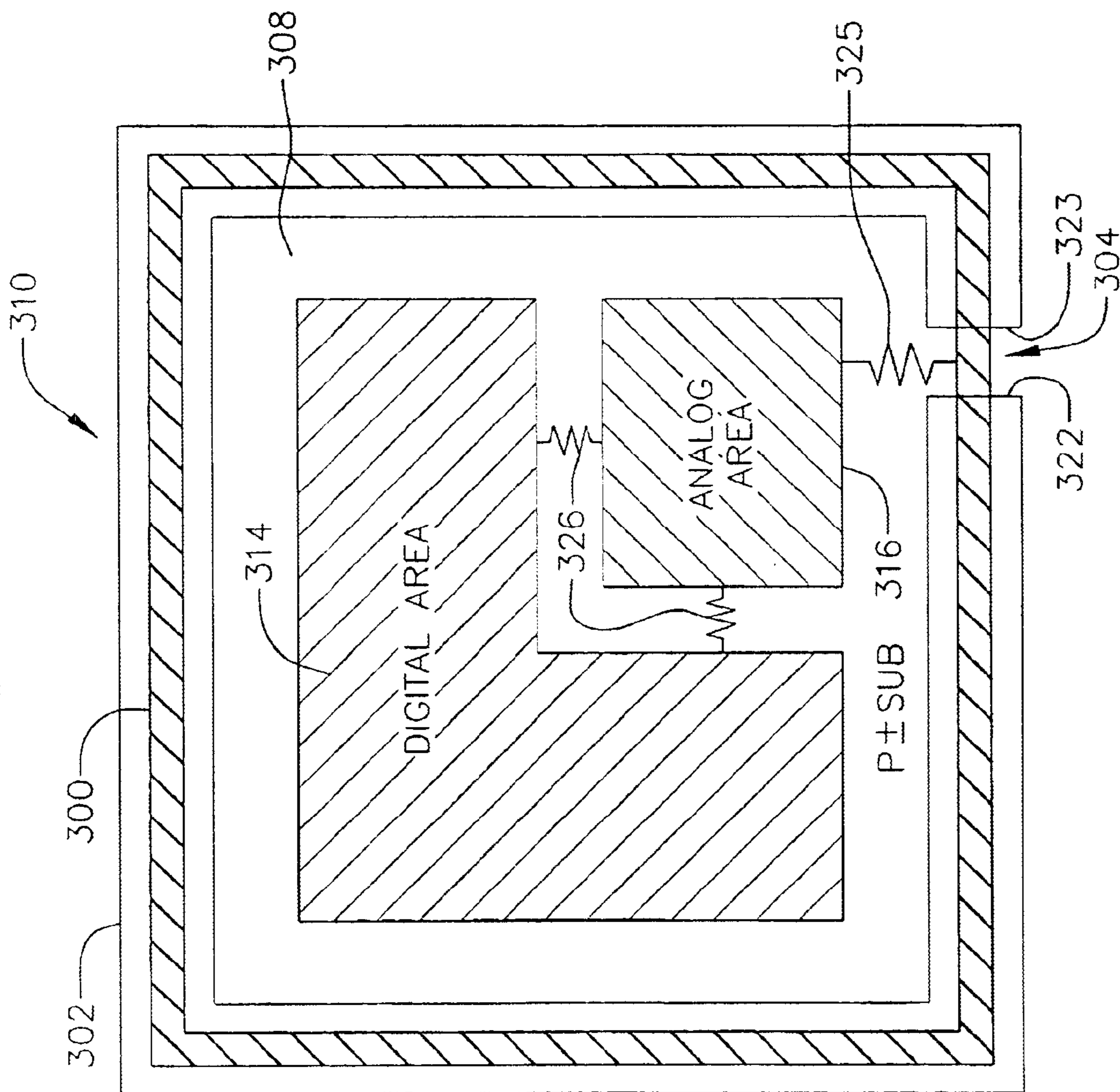


FIG. 3



SEAL RING FOR INTEGRATED CIRCUITS**CROSS-REFERENCES TO RELATED APPLICATIONS**

This application claims priority from U.S. Provisional Patent Application Ser. No. 60/191,341 filed Mar. 22, 2000, the disclosure of which is incorporated herein by reference for all purposes.

BACKGROUND OF THE INVENTION**1. Field of the Invention**

The present invention relates generally to the manufacture of integrated circuits and more particularly, to a seal structure for a semiconductor die that improves substrate isolation.

2. Description of the Prior Art

Most semiconductor integrated circuit manufacturers require a seal ring at the periphery of the semiconductor die. The seal ring circumscribes the periphery of the semiconductor die and is in contact with the die. The seal ring surrounds the bonding pads, which are typically disposed along the outer edges of the die. The seal ring creates a barrier to penetration of moisture, corrosive gasses, and chemicals.

A conventional seal ring is a multi-layer structure composed of alternating conducting and insulating layers. Through each of the insulating layers run multiple vias which provide electrical paths between adjacent metal layers. The lowest layer of metal in the seal structure makes electrical contact with the substrate, which can be either p-type or n-type. This structure ensures that no oxide path is presented to the edges of the semiconductor die after the semiconductor die has been diced (i.e., cut into individual dies from a wafer).

While this seal structure provides an effective barrier to undesirable environmental effects, it presents a problem that can be severe in certain circuit applications. Specifically, the seal ring creates a substrate short-circuit path all the way around the semiconductor die because multiple sections of the semiconductor die make electrical contact with the seal ring. In the case of mixed signal integrated circuits, which integrate both analog and digital circuits on the same substrate, circuit designers take careful measures to isolate the noisy portions of the substrate that include the digital circuitry from the section of the substrate that carries the noise sensitive analog circuitry. This is usually accomplished by placing substrate barriers and substrate islands around different parts of the circuitry in order to isolate the more noisy circuit areas of the substrate from other areas that are more noise sensitive.

Isolating different circuitry areas on the substrate is effective in terms of directly isolating various portions of the circuitry from each other, but it does not address the short-circuit path between different portions of the circuitry provided by the seal ring. The seal ring provides a very low resistance metal path between different areas of the circuitry around the periphery of the substrate. Providing this path on which noise can travel from noisy areas of circuitry to noise sensitive areas defeats the attempts made to directly isolate the noisy digital areas of the substrate from the more noise sensitive analog areas.

SUMMARY OF THE INVENTION

The present invention is directed to a seal structure and method for forming a seal structure for a semiconductor die.

An elongate region that is electrically isolated from the remainder of the substrate, such as a well region of a conductivity type opposite that of the substrate, extends around the major portion of the periphery of the substrate. A gap is left between the two ends of the elongate region along the minor portion of the periphery of the substrate not covered by the elongate region. A conductive seal ring is formed around the periphery of the substrate at the elongate region and spans the gap between the ends of the elongate region. The substrate of the semiconductor die is only brought into electrical contact with the seal ring at the gap between the ends of the elongate region.

Allowing the substrate to electrically contact the seal ring only at a minor portion of the seal ring ensures that the short circuit between the seal ring and the substrate is limited to a small portion of the semiconductor die. Thus, the only low resistance electrical path between the substrate and the seal ring is confined to the small portion of the seal ring in electrical contact with the gap in the elongate region. With only one low resistance electrical path between the seal ring and the substrate, the seal ring no longer behaves as a conductive ring interconnecting all areas of the semiconductor die. The direct contact between the seal ring and the substrate at the gap is sufficient, however, to prevent the seal structure from accumulating charge while being manufactured. The location of the minor portion of the seal ring that contacts the substrate can be adjusted and optimized according to the specific circuit requirements. For example, in some applications it might be desirable to place the portion of the seal ring that contacts the substrate near the noisy area, or vice versa.

As mentioned above, the substrate and the well region of the preferred embodiment are formed having opposite conductivity types. The present invention allows for the substrate to have either a p-type or n-type conductivity, and the elongate region may be a well having either an n-type or p-type conductivity, respectively. Forming a well region with a conductivity opposite that of the substrate of the semiconductor die, and bringing the majority of the seal ring into physical contact only with the well region, reduces the ability of the semiconductor to communicate electrical signals, more specifically noise, through the seal ring to noise sensitive areas of the semiconductor die, without diminishing the protective benefits of the seal ring during manufacture of the die and during use of the semiconductor.

Other embodiments that isolate the seal ring from all or most of the substrate are also possible. For example, instead of the elongate well region, a high quality dielectric may be placed under the seal ring to electrically isolate it from the substrate. In another embodiment, the seal ring is electrically isolated from the substrate along the entire periphery of the die, and a separate low resistance path is provided between the seal ring and a power supply node to avoid a floating seal ring.

The novel features that are characteristic of the invention, as to organization and method of operation, together with further objects and advantages thereof, will be better understood from the following description when considered in connection with the accompanying drawings in which a preferred embodiment of the invention is illustrated by way of example. It is to be expressly understood, however, that the drawings are for the purpose of illustration and description only and are not intended as a definition of the limits of the invention.

BRIEF DESCRIPTION OF THE DRAWINGS

FIG. 1 is a schematic cross sectional view of a prior art seal ring and substrate;

FIG. 2 is an overhead view of the prior art seal structure of FIG. 1; and

FIG. 3 is an overhead view depicting the preferred embodiments of the seal structure of the present invention.

DESCRIPTION OF THE SPECIFIC EMBODIMENTS

A prior art semiconductor die **210** employing a seal ring structure **200** formed on a substrate **208** is illustrated by way of reference to FIG. 1. Seal ring **200** is composed of alternating conductive metal layers **203** and insulating layers **204**. Each insulating layer **204** contains one or more vias **206** extending through the insulating layer and providing a conductive path between various metal layers **203**. The lowest conductive metal layer **203'** of seal **200** contacts substrate **208** through vias **206'** to provide a relatively low resistance conductive path between the seal ring and the substrate of semiconductor die **210**. Substrate **208** is typically silicon, but may consist of other materials.

FIG. 1 shows substrate **208** as having a p-type conductivity. Alternatively, substrate **208** could have an n-type conductivity. In either event, substrate **208** is rendered partially conducting. Dicing discharging paths **212** are created in substrate **208** at the point at which the lowest conductive metal layer **203'** of seal ring **200** contacts the substrate. Dicing refers to the industry process of configuring a wafer into individual dies. Discharge paths **212** discharge charge in the substrate which has accumulated during manufacture of the semiconductor die.

As illustrated in FIG. 2, semiconductor die **210** has mixed signal integrated circuits, and two distinct circuit areas are located on substrate **208**. Digital circuit area **214** contains a variety of digital circuits. Digital circuit area **214** is L shaped and occupies the majority of the area enclosed by seal **200**. Analog circuit area **216** is also located on substrate **208** and contains a variety of analog circuits. Analog circuit area **216** is square and occupies the area enclosed by seal ring **200** not occupied by digital circuit area **214**.

The digital circuits located in digital circuit area **214** characteristically create a relatively large amount of noise, to which the digital circuits themselves are not susceptible. The analog circuits in analog circuit area **216**, however, are noise sensitive, i.e., they are prone to errors in the presence of noise. Digital circuit area **214** and analog circuit area **216** are prevented from transmitting noise directly to one another by substrate barriers or substrate islands (not shown) between the respective areas.

The region of the substrate **208** between the digital circuit area **214** and the conductive ring seal **200** provides partially conductive paths between the digital circuit area and the ring seal represented by resistor symbols **218**. While the noise generated by the digital circuits is typically isolated so that it cannot directly reach the noise sensitive analog circuits in analog circuit area **216**, such noise can reach conductive seal ring **200** through the conductive paths in the substrate represented by resistor symbols **218**.

Analog circuit area **216** has a plurality of dicing discharging paths represented by resistors **220** between the analog circuit area and seal ring **200**. These dicing discharging paths **220** allow the noise generated by the digital circuit area **214** and carried on conductive ring seal **200** to enter analog circuit area **216**. This prior art implementation of the seal ring thus has the undesirable effect of transmitting noise from relatively high noise digital circuits to noise sensitive analog circuits in mixed signal integrated circuits.

FIG. 3 schematically illustrates a preferred embodiment of the semiconductor die **310** and seal ring **300** of the present

invention. An elongate region **302** is formed in substrate **308** that extends around the majority of the periphery of semiconductor die **310**. A gap **304** remains between the two ends **322, 323** of elongate region **302**. In a preferred embodiment of the present invention, elongate region **302** constitutes an elongate well region having a conductivity type opposite from that of the substrate. If substrate **308** is p-type, the well region **302** is n-type, and vice versa. Alternatively, elongate region **302** may comprise a high quality dielectric layer that provides electrical insulation.

Seal ring **300** extends around the periphery of semiconductor die **310** and encompasses the digital circuit area **314** and the analog circuit area **316**. The seal ring **300** of the preferred embodiment has the same structure as prior art seal ring **200** shown in FIG. 1. Seal ring **300** physically connects the substrate along the entire length of elongate region **302**. Seal ring **300** also physically contacts the substrate at the gap **304** between the ends **322, 323** of elongate region **302**. Substrate **308** makes electrical contact with seal ring **300** solely at the gap **304** where the substrate physically contacts the seal ring without the intervening well region **302** of opposite conductivity type (or other insulator). A single partially conducting path illustrate by resistor **325** extends through substrate **308** to the section of seal ring **302** in electrical contact with the substrate at gap **304**.

The electrical conductivity between the digital circuit area **314** and the analog circuit area **316** is highly restricted by barriers and islands in the substrate, as illustrated by small resistor symbols **326**. Elongate region **302** restricts the electrical contact between seal ring **300** and the digital and analog circuit areas **314** and **316** except at the gap **304** in the elongate region. Nonetheless, seal ring **302** prevents substrate **308** from accumulating charge during the manufacturing and dicing of semiconductor die **310**. Although seal ring **300** is electrically isolated by elongate region **302**, seal ring **300** maintains its ability to protect the various circuit areas from the penetration of moisture, corrosive gasses, and chemicals that might be present in the environment.

In operation, the digital circuits in digital circuit area **314** will create noise, which does not inhibit the proper operation of the digital circuits themselves. Features in substrate **308** between the respective areas will effectively prevent the noise generated by the digital circuits from reaching the noise sensitive analog circuits in analog circuit area **316**. Because electrical contact between substrate **308** and seal ring **300** is inhibited by elongate region **302** except at the gap **304** located far from digital circuit area **314**, the seal ring **302** does not provide a short circuit to transmit such noise and little of the noise generated by the digital circuits will reach analog circuit area **316**. Yet, the limited electrical contact between substrate **308** and seal ring **300** at gap **304** allows the seal ring to perform its discharge function.

While a preferred embodiment of the present invention has been illustrated in detail, it is apparent that modifications and adaptations of that embodiment will occur to those skilled in the art. For example, while elongate region **302** has been shown as a well region, the elongate region could be a high quality dielectric region or other insulative feature and a separate low resistive path provided between the seal ring and a power supply node to avoid a floating seal ring. Also, the gap between the ends of the elongate region can be near or far from the noisy circuit areas as needs require. However, it is to be expressly understood that such modifications and adaptations are within the spirit and scope of the present invention, as set forth in the following claims.

What is claimed is:

1. A die seal structure for a semiconductor die having a substrate comprising:

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an elongate region extending around a major portion of the periphery of the substrate and having a gap between ends of the elongate region along a minor portion of the periphery, the elongate region being of high resistivity from the remainder of the substrate except at the gap; and

a passive conductive seal ring extending around the entire periphery of the die within the elongate region and in direct contact with the substrate only at the gap.

2. The structure of claim 1 wherein the substrate has a first conductivity type, and wherein the elongate region comprises an elongate well region of a second conductivity type different from the conductivity of the first conductivity type.

3. The structure of claim 2 wherein the first conductivity type is p-type and the second conductivity type is n-type.

4. The structure of claim 2 wherein the first conductivity type is n-type and the second conductivity type is p-type.

5. The structure of claim 1 wherein the elongate region comprises an elongate dielectric region between the passive conductive seal ring and the substrate.

6. The structure of claim 1 wherein the substrate is formed of silicon.

7. The structure of claim 1 wherein the passive conductive seal ring comprises a multilayer structure of alternating conducting and insulating layers, and wherein vias are formed in the insulating layers.

8. A die seal structure for a semiconductor die having a substrate of a first conductivity type, comprising:

an elongate well region of a second conductivity type opposite from the first conductivity type extending around a major portion of the periphery of the substrate and having a gap between the ends of the elongate region along a minor portion of the periphery, the elongate well region being of high resistivity from the remainder of the substrate except at the gap; and

a passive conductive seal ring extending around the entire periphery of the die within the elongate well region and in direct contact with the substrate only at the gap.

9. The structure of claim 8 wherein the first conductivity type is p-type and the second conductivity type is n-type.

10. The structure of claim 8 wherein the first conductivity type is n-type and the second conductivity type is p-type.

11. The structure of claim 8 wherein the passive conductive seal ring comprises a multilayer structure of alternating

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conducting and insulating layers, and wherein vias are formed in the insulating layers.

12. A semiconductor device comprising:

a. a die including a substrate;

b. a die seal structure on the substrate, the structure comprising:

an elongate region extending around a major portion of the periphery of the substrate and having a gap between ends of the elongate region along a minor portion of the periphery, the elongate region being of high resistivity from the remainder of the substrate except at the gap; and

a passive conductive seal ring extending around the entire periphery of the die within the elongate region and in direct contact with the substrate only at the gap.

13. The structure of claim 12 wherein the substrate has a first conductivity type, and wherein the elongate region comprises an elongate well region of a second conductivity type different from the conductivity of the first conductivity type.

14. The structure of claim 12 wherein the first conductivity type is p-type and the second conductivity type is n-type.

15. The structure of claim 12 wherein the first conductivity type is n-type and the second conductivity type is p-type.

16. The structure of claim 12 wherein the elongate region comprises an elongate dielectric region between the passive conductive seal ring and the substrate.

17. The structure of claim 12 wherein the substrate is formed of silicon.

18. The structure of claim 12 wherein the passive conductive seal ring comprises a multilayer structure of alternating conducting and insulating layers, and wherein vias are formed in the insulating layers.

19. The structure of claim 12 wherein the elongate region is isolated by oxide.

20. The structure of claim 19 wherein the passive conductive seal ring is connected to the substrate by a metal stub.

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